

<b>LIST OF REFERENCES CITED BY APPLICANT</b> <i>(Use several sheets if necessary)</i>		ATTY. DOCKET NO. 9875-0008-999	APPLICATION NO. To be assigned
		APPLICANT Hagelin et al.	
		FILING DATE July 25, 2003	GROUP 2872

**U.S. PATENT DOCUMENTS**

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
J.P.	5,867,297	2/1999	Kiang et al.			
J.P.	5,629,790	5/1997	Neukermans et al.			
J.P.	5,408,352	4/1995	Peng			
J.P.	4,317,611	3/1982	Peterson			
J.P.	5,361,158	11/1994	Tang			
J.P.	5,998,906	12/1999	Jerman et al.	310		

**FOREIGN PATENT DOCUMENTS**

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

**OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)**

J.P.	Daneman et al., "Integrated Laser-to-Fiber Coupling Module Using a Micromachined Alignment Mirror", <i>Conference on Lasers and Electro-Optics, 1995, Technical Digest Series, Vol. 15, pp.245-250, Baltimore, MD, May 1995.</i>
J.P.	Daneman et al., "Linear Microvibromotor for Positioning Optical Components", <i>J of Microelectromechanical Systems, 5(3):159-163 (1996).</i>
J.P.	Daneman et al., "Linear Vibromotor-Actuated Micromachined Microreflector for Integrated Optical Systems", <i>Solid-State Sensor and Actuator Workshop, Hilton Head, SC, June 2-6 1996.</i>
J.P.	Deng et al., "The Development of Polysilicon Micromotors for Optical Scanning Applications", <i>Solid-State Sensor and Actuator Workshop, pp. 234-238, Hilton Head, SC, June 13-16, 1994.</i>
J.P.	Kiang et al., "Electrostatic Combdrive-Actuated Micromirrors for Laser-Beam Scanning and Positioning", <i>J of Microelectromechanical Systems, 7(1):27-37, March 1998.</i>
J.P.	Kiang et al., "High-Precision Si-Micromachined Micromirrors with On-Chip Actuation for External-Cavity Semiconductor Lasers", <i>Conference on Lasers and Electro-Optics, Technical Digest Series, Vol. 15, pp. 248-249, Baltimore, MD, May 1995.</i>
J.P.	Kiang et al., "Micromachined Polysilicon Microscanners for Barcode Readers", <i>IEEE Photonics Technology Letters, 8(12):1707-1709, December 1996.</i>
J.P.	Kiang et al., "Silicon-Micromachined Micromirrors with Integrated High-Precision Actuators for External-Cavity Semiconductor Lasers", <i>IEEE Photonics Technology Letters, 8(1):95-97 (1996).</i>
J.P.	Pister et al., "Microfabricated Hinges", <i>Sensors and Actuators, 33(3):249-256 (1992).</i>
J.P.	Solgaard, O., "High-Resolution Silicon Surface Micromachined Displays", (invited talk), <i>Technical Digest of the IEEE/LEOS IEEJ/SAMS 1997 International Conference on Optial MEMS and their Applications (MOEMS97), pp. 9-14, Nara, Japan, November 18-21, 1997.</i>
J.P.	Solgaard et al., "Optoelectronic Packaging Using Silicon Surface-Micromachined Alignment Mirrors", <i>IEEE Photonics Technology Letters, 7(1):41-43 (1995).</i>
J.P.	Solgaard et al., "Precision and Performance of Polysilicon Micromirrors for Hybrid Integrated Optics", <i>SPIE, Symposium on Lasers and Applications, San Jose, CA, February 1995.</i>
J.P.	Tien et al., "Surface-Micromachined Mirrors for Laser-Beam Positioning", <i>Sensors and Actuators, A 52:76-80 (1996).</i>
J.P.	Tsufura et al., "Barcode Scanning On-Going Evolution & Development", <i>Lasers &amp; Optronics, July 1995.</i>

J.P-		Yasseen et al., "Diffraction Grating Scanners Using Polysilicon Micromotors", <i>Proceedings IEEE Micro Electro Mechanical Systems</i> , pp. 175-180, Amsterdam, The Netherlands, January 1995.
J.P-		Lin et al. "Free-Space Micromachined Optical Switches with Submillisecond Switching Time for Large-Scale Optical Crossconnects" <i>IEEE Photonics Technology Letters</i> , Vol. 10, No. 4, April 1998, pp 525-527.

EXAMINER	James Phan	DATE CONSIDERED	5/17/04
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			